P29662.P05 Sheet 1 of 1

FORM PTO-1449
U.S. Department of Commerce Patent and Trademark Office P29662

INFORMATION DISCLOSURE STATEMENT

Applicant

Aty. Docket d. P29662

Application No. 10/583,124 O 1 P-E

NFORMATION DISCLOSURE STATEMENT
BY APPLICANT
(Lieu saveral sheets if necessary)

Applicant
Bernd SZYSKA et al.

SEP 2 8 2007

Filing Date
Descriptor 20 2004

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/RM/		Vergohl et al., "Real Time Control of Reactive Magnetron-Sputter Deposited Optical Filters By In Situ Spectroscopic Ellipsometry," Thin Solid Films, vol. 377-378, December 1, 2000, pages 43-47.													
/RM/	1	Vergohl et al., "In Situ Monitoring of Optical Coatings on Architectural Glass and Comparison of the Accuracy of the Layer Thickness Attainable with Ellipsometry and Photometry," <u>Thin Solid Films</u> , vol. 392, no. 2, July 30, 2001, pages 258-264.													
/RM/	J	J. Affinito et al., J. Vac. Sci. Technol. A 2 (1984), p. 1275-1284.													
/RM/	E	J. Strümpfel, Prozessstabilisierung beim reaktiven Hochratenzerstäuben mittels optischer Emissionsspektroskopie zur industriellen Herstellung von Indium-Zinn-Oxidschichten und Titandioxidschichten, Chemnitz 1991.													
/RM/	S	. Ber	g, <u>J.</u>	Vac.	Sci.	Tec	hnol	<u>.</u> A 10 (1992), p. 1592-1	596.					

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